

**Amendments to the Specification:**

Please replace paragraph 0032 with the following:

Figures 4-8 schematically illustrate a microfeature workpiece holder 100 in accordance with one embodiment of the invention. This microfeature workpiece holder 100 generally includes a base 110, a plurality of columns 120, and a cap 150. The particular embodiment shown in Figures 4-8 employs 3 columns, namely columns 120a, 120b and 120c. The base 110 and the cap 150 are each generally semicircular in shape and the columns 120a-c are spaced approximately 90° from one another so that the two outer columns 120a and 120c are generally diametrically opposed to one another. It should be recognized that this is simply one possible embodiment that may be useful in connection with microfeature workpieces that are generally circular in shape. In other embodiments, more or fewer columns 120 may be employed. In addition, the base 110 and/or the cap 150 may take the form of a solid plate or disk or have any other desired shape. In other embodiments, only one of the base 110 or cap 150 is employed. For example, the cap 150 may be omitted and the base 110 may provide the requisite support for the columns 120.

Please replace paragraph 0042 with the following:

One difference between the microfeature workpiece holders 100 and 102 relates to the design of the gas distributor. The gas distributor 130 shown in Figure 5 employs a single gas inlet 140 that communicates with each of the gas delivery conduits 134a-c through a common manifold 132. The microfeature workpiece holder 102 of Figure 9 does not include a manifold 132. Instead, the gas distributor 131 in Figure 9 has a separate gas inlet 140 for each of the gas delivery conduits 134. Hence, one inlet 140a is in fluid communication with a first one of the gas delivery conduits 134a, a second gas inlet 140b is in fluid communication with a second gas delivery conduit 134b, and a third gas inlet 140c is in fluid communication with a third gas delivery conduit 134c. In this design, each of the gas delivery conduits 134 may be adapted to delivery a process gas flow that is independent of the process gas flow delivered through each of the other

conduits 134. As noted below, this may permit a different process gas to be delivered through each of the conduits 134a-c. In the context of the ALD process outlined above in connection with Figures 1 and 2, for example, one of the gas delivery conduits (e.g., conduit 134a) may be dedicated to delivering the first precursor gas A, a second one of the gas delivery conduits (e.g., conduit 134b) may be used to deliver the second precursor gas B, and the third gas delivery conduit 134c may be used to deliver the purge gas.

Please replace paragraph 0053 with the following:

The flow of gas through the supply line 356 to the gas distributor 130 of the holder 100 may be controlled, at least in part, by a main valve 362 that is under the control of a controller 370. The controller 370 may take any of a variety of forms. In one embodiment, the controller 370 comprises a computer having a programmable processor programmed to control operation of the system 300 to deposit material on the workpieces W. The controller 370 may also be operatively coupled to the secondary valves 354a-c to control the composition of the gas delivered to the main valve 362 via the supply line 356. The controller 370 may also be coupled to the vacuum 340 (as illustrated) or any other component of the processing system 300, e.g., the heater 330.